DETERMINATION OF THE SPIN DIFFUSION LENGTH IN SILICON AT LOW TEMPERATURES

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Outline

- Spintronics, GMR (giant magnetoresistance) and basic concepts related to injection of spin polarized currents
- Spin injection in permalloy clusters on silicon
- L_{SD} obtained from Ni/Al₂O₃/Si ferromagnetic nanocontacts
- conclusion

Spintronics – technology based on the injection of spin-polarized currents into metals and semiconductors

Challenges – injection and detection of spin polarized currents with high efficiencies



GMR

Is the change in electrical resistance of layered F/N/F systems when the magnetization of the ferromagnetic layers are reoriented to one another by the application of a magnetic external field.

F

$$MR = \frac{\Delta R}{R^F} = \frac{R^{AF} - R^F}{R^F}$$

GMR

Originates from the spin dependent electronic transport intrinsic to metal systems

Spin dependent electronic transport can be qualitatively understood using the Mott model that has 2 main points:

1. The electrical conductivity in metals can be described by 2 independent conducting channels, corresponding to up- and down-spin electrons The probability of spin-flip scattering is normally small than the probability of scattering with conservation of spin, i. e. up- and down-spin do not mix over long distances.

GMR

2. In ferromagnetic metals the scattering rates of up- and down-spin electrons are quite different, whatever be the nature of the scattering centers.



The electric current is primarily carried by electrons from *sp* bands due to their low effective mass and high mobility. The *d* bands provide the final states for scattering of the *sp* electrons.

In ferromagnets the *d* band have exchange-split, and the density of states (DOS) is not the same for up- and down-spin electrons at the Fermi level. The probability of scattering into these states is proportional to their density, such that the scattering rates are spin dependent.

Ferromagnetic/non-ferromagnetic interface





conductivity

 $\sigma_{\uparrow(\downarrow)} = e^2 N_{\uparrow(\downarrow)}(E_F) D_{\uparrow(\downarrow)}$

N = density of levels

D = diffusion coefficient

polarization

$$P_{\text{corrente}} = \frac{\sigma_{\uparrow} - \sigma_{\downarrow}}{\sigma_{\uparrow} + \sigma_{\downarrow}}$$

Valet and Fert model

1. Current flowing perpendicular to the plane (CPP) F N

2. Take into account the diffusive spin transport through the interface (the current is spin polarized well beyond the ballistic range)

- 3a. Metal/metal case: DOS_F≈DOS_N
- 3b. Metal/semicond. case: DOS_F>>DOS_S (conductivity mismatch)

G. Schmidt *et al.*, "Fundamental obstacle for electrical spin injection from a ferromagnetic metal into a diffusive semiconductor," *Phys. Rev. B, Condens. Matter*, vol. 62, no. 8, pp. R4790–R4793, Aug. 2000.

A. Fert, J.-M. George, H. Jaffrès, and R. Mattana IEEE TRANSACTIONS ON ELECTRON DEVICES, VOL. 54, NO. 5, MAY 2007

L_{SD} = spin diffusion length



Using a tunnel barrier at the interface to balance the number of spin flips in F and N, restoring the spin polarization of the electric current.

The conditions for an efficient spin injection are:

$$r_1 = \rho_N t_N << r_b << \rho_N \frac{(L_{SD}^N)^2}{t_N} = r_2$$

 r_b = barrier specific area resistance r_1 and r_2 are lower and upper limits for r_b

 ρ_N resistivity of semiconductor t_N distance between contacts $r_N = \rho_N L^N_{SD}$ and $r_F = \rho_F L^F_{SD}$

Rashba, PRB 62, R16267 (2000) Fert and Jaffrès, PRB 64, 184420 (2001)





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$$MR = \frac{\Delta R}{R} = \frac{\gamma^2 / (1 - \gamma^2)}{1 + r_b / r_2}$$

 γ = spin asymmetry interface coefficient

Results from de literature



Y. Q. Jia, Rick C. Shi, and Stephen Y. Chou, IEEE TRANS. on MAGNETICS. 32 (1996)

Fabrication of the samples – first approach

Electrodeposition



Permalloy: ferromagnetic alloy with 80% Ni and 20% Fe

Electrodeposition of FeNi (Py) clusters on silicon



Deposition time t = 8 s

Py/Si system - Electrical measurements



Py/Si system - MR measurements (room temperature)



Py/Si system - MR measurements (room temperature)





Py/Si system with an Au layer





Fabrication of the samples – second approach

Nanofabrication



Electron beam lithography (CBPF/RIO de Janeiro)

- Ni and Al₂O₃ evaporated
- t_N from 100 nm up o 1450 nm
- $\rho_{n-Si} = 1 \times 10^{15} \Omega.cm^{-3}$



Results for nanocontacts









Conclusions:

- ✓ High MR values (up to 75%) at temperatures below 35 K
- Results follow very well the model developed by Valet and Fert with a tunnel barrier at the interface introduced by Fert and Jaffrès that consider the spin injection as a diffusional process
- ✓ Determination of L_{sf}^{N} varying in the range from 200 nm to 700 nm for temperatures decreasing from 35 K to 10 K (n-Si with a resistivity of 10¹⁵ cm^{-3.}
- ✓ The dependency of the silicon resistance with the temperature is main factor contributing to the upper limit of the resistance window, where the GMR exists.

Thank you for the attention!